

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	164	(microstructures or micromachine) same etch\$3 same vapor	USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/05/04 07:42
L2	267	(microstructures or micromachine or MEMS) same etch\$3 same vapor	USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/05/04 09:28
L4	28	(microstructures or micromachine or MEMS) same (vapor with etch)	USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/05/04 07:52
L5	243	(microstructures or micromachine or MEMS) and (vapor with etch)	USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/05/04 07:52
L6	97	(microstructures or micromachine or MEMS) and (vapor with etch) and (recipe or parameters)	USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/05/04 09:05
L7	1	"5302238".PN.	USPAT; USOCR	OR	OFF	2005/05/04 09:04
L8	273	(microstructures or micromachine or MEMS) same (aluminum or copper) same TiN	USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/05/04 09:08
L11	778	(microstructures or micromachine or MEMS) and (etch\$3 or remov\$3) and (vapor with etch\$3)	USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/05/04 09:30
L12	263	(microstructures or micromachine or MEMS) and (etch\$3 or remov\$3) and (vapor with etch\$3) and (HF or "xeF.sub.2" or "xenon difluoride" or "bromine trichloride")	USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/05/04 09:32
L13	400	(microstructures or micromachine or MEMS) and (etch\$3 or remov\$3) and (vapor with etch\$3) and (recipe or window or parameters)	USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/05/04 09:32